PTO/SB/21 (04-04)

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TRANSMITTAL FORM

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Total Number of Pages in This Submission

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Signature

Joan I. Abriam

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Application Number	10/809,317	
Filing Date	03/24/2004	
First Named Inventor	G. Ramanath	
Art Unit	2813	
Examiner Name	Kielen, Erik J	
Attorney Docket Number	5002.02-1	

	ENCLOSURES (check a	all that apply)
Fee Transmittal Form	Drawing(s)	After Allowance communication to Technology Center (TC)
Fee Attached	Licensing-related Papers	Appeal Communication to Board of Appeals and Interferences
Amendment / Reply	Petition	Appeal Communication to TC (Appeal Notice, Brief, Reply Brief)
After Final	Petition to Convert a Provisional Application	Proprietary Information
Affidavits/declara	on(s) Power of Attorney, Revocation Change of Correspondence of	
Extension of Time Reque	Terminal Disclaimer	Other Enclosure(s) (please identify below):
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under 37 CFR 1.	? or 1.53	
	GIGNATURE OF APPLICANT, ATTORNEY,	OR AGENT
Firm David J. A Reg. No. 3		
Signature	~ /Ah	
Date December	29, 2004	

This collection of information is required by 37 CFR 1.5. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to 12 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Date

December 29, 2004

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Ser. No. 10/809,317

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

: G. Ramanath, et al.

Art Unit.

: 2813

Serial Number : 10/809,317

Examiner: Kielen, Erik J

Filed

03/24/2004

Title

: Diffusion Barriers

Comprising Self-

Confirmation

**Assembled Monolayers** 

Customer

Number

: 6500

Number : 23308

CERTIFICATE OF MAILING or FACSIMILE TRANSMISSION UNDER 37 C.F.R. § 1.8(a)(1) I hereby certify that this correspondence (along with any referred to as being attached or enclosed) is, on the date shown below, being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to Mail Stop IDS, Commissioner for Patents, P.O. Box 1450, Alexandria Virginia, 22323-1450, or facsimile transmitted to the U.S. Patent and Trademark Office on the date shown below.

Dated: 12/29/2004

Printed Name: Joan I. Abriam

## TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR § 1.97

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.97 and § 1.98, Applicants submit for consideration in the above-identified application the documents listed on the attached Form PTO-1449. Copies of the documents were previously properly submitted in an Information Disclosure Statement and/or Office Action, directed to the related application Serial Number 09/976,927, filed 10/11/2001, now abandoned, and, accordingly, copies are not included herewith. This protocol conforms with 37 C.F.R. §1.98(d) and M.P.E.P. 609(A)(2). The Examiner is requested to make these documents of record in the application.

This Information Disclosure Statement is submitted:

Within three months of the application filing date or before mailing of a first Office Action on the merits; accordingly, no fee or separate requirements are applicable.

Applicants would appreciate the Examiner initialing and returning the Form PTO-1449, indicating that the information has been considered and made of record herein.

The information contained in the Information Disclosure Statement under 37 C.F.R. § 1.97 is not to be construed as a representation that: (i) a complete search has been made; (ii) additional information material to the examination of this application does not exist; (iii) the information, protocols, results and the like reported by third parties are accurate or enabling; or (iv) the above information constitutes prior art to the subject invention.

The dates of the references are provided relative to the effective filing date of the present application in accordance with M.P.E.P. § 702 III.IV, having the earliest priority filing date of 10/11/2001.

In the unlikely event that the transmittal letter is separated from this document and the Patent Office determines that an extension and/or other relief is required, applicant petitions for any required relief including extensions of time and authorizes the Assistant Commissioner to charge the cost of such petitions and/or other fees due in connection with the filing of this document to Deposit Account No. 16-1331.

This submission is accompanied by a Transmittal Form, 1 Form 1449 and copies of the following references:

Three of the references were not considered properly submitted in the parent case. Accordingly, paper copies of the following references are being supplied herewith:

Ser. No. 10/809,317

- AQ Reed, MA. and Tour, J.M., "Computing with molecules," Scientific American, June 2000, pp. 86-93, Vol. 282(6).
- AR Sekiguchi, A. et al., "Microstructual and morphological changes during thermal cycling of Cu thin films, "J. Japan Inst. Metals, April 2000, pp. 379-382, Vol. 64 (5).
- AU Moshfegh, A.Z. et al., "Bias sputtered Ta modified diffusion barrier in Cu/Ta(V<sub>b</sub>/Si(111)) structures," Thin Solid Films, July 2000, pp 10-17, Vol. 370.

In accordance with M.P.E.P \$609.III, Minimum Requirements For an Information Disclosure Statement, copies Of U.S. patents cited herein are not included since this application was filed after June 23, 2003. Also, no copy of any cited U.S. patent application is included, in accordance with USPTO Notice dated September 21, 2004, http://www.uspto.gov/web/offices/pac/dapp/opla/preognotice/rule98waiverd.pdf.

Respectfully submitted,

PETERS, VERNY, JONES & SCHMITT, LLP

David J. Aston, Reg. No. 28,051

Tel.: (650) 324-1677 Fax: (650) 324-1678

PTO/SB/08A (10-01)

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1449A/PTO Substitute for

Sheet

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## ORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

of 2

Complete if Known		
Application Number	10/809,317	
Filing Date	03/24/2004	
First Named Inventor	G. Ramanath	
Group Art Unit	2813	
Examiner Name	Kielen, Erik J	
Attorney Docket Number	5002 02-1	

Examiner	Cite	Document Number	Publication Date/	Name of Patentee or Applicant of	Pages, Columns, Lines, Where Relevan
Initials *	No.1	Number - Kind Code <sup>2</sup> (if known)	Issue Date MM-DD-YYYY	Cited Document	Passages or Relevant Figures Appear
	AA	US - 4,996,075	02-1991	Ogawa et al.	
	AB	US - 5,057,339	10-1991	Oawa, Kazufumi	
	AC	US - 5,077,085	12-1991	Schnur et al.	
	AD	US - 5,079,600	01-1992	Schnur et al.	
	AE	US - 5,389,496	02-1995	Calvert et al.	•
	AF	US - 5,468,597	11-1995	Calabrese et al.	
	AG	US - 5,500,315	03-1996	Calvert et al.	
	AH	US - 5,510,216	04-1996	Calabrese et al.	
	Al	US - 5,648,201	07-1997	Dulcey et al.	
	AJ	US - 5,939,150	08-1999	Stelzle et al.	•
	AK	US - 6,348,240 B1	02-2002	Calvert et al.	

	FOREIGN PATENT DOCUMENTS					
Examiner	Cite	Foreign Patent Document		Name of Patentee or	Pages, Columns, Lines, Where Relevant	
Initials*	No.1	Country Code <sup>3</sup> - Number <sup>4</sup> - Kind Code <sup>5</sup> (if known)	Publication Date MM-DD-YYYY  Applicant of Cited Document		Passages or Relevant Figures Appear	T <sup>6</sup>

		OTHER PRIOR ART NON PATENT LITERATURE DOCUMENTS	
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
	AL	Ahrens, C. et al., "Electrical characterization of conductive and non-conductive barrier layers for Cu-metallization," Applied Surface Science, 1995, pp. 285-290, Vol. 91.	
	AM	Ding, P.J. et al., "Effects of the addition of small amounts of Al to copper: Corrosion, resistivity, adhesion, morphology, and diffusion," J. Appl. Phys., April 1994, pp. 3627-3631, Vol. 75(7).	
	AN	Ding, P.J. et al., "Oxidation resistant high conductivity copper films," Appl. Phys. Lett. May 1994, pp. 2897-2899, Vol. 64(21).	
	AO	McBrayer, J.D. et al., "Diffusion of metals in silicon dioxide," J. Electrochem. Soc., June 1986, pp. 1242-1246, Vol. 133(6).	
	AP	Raghavan, G. et al., "Diffusion of copper through dielectric films under bias temperature stress," Thin Solid Films, 2995, pp. 168-176, Vol. 262.	

Examiner Signature	Date Considered	

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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<sup>&</sup>lt;sup>1</sup> Applicant's unique citation designation number (optional) . <sup>2</sup> See Kinds Codes of USPTO Patent Documents at <u>www.uspto.gov</u> or MPEP 901.04. <sup>3</sup> Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup> For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. 5 Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. <sup>6</sup> Applicant is to place a check mark here if English language Translation is attached.

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Substitute for form 1449A/PTO Complete if Known 10/809,317 Application Number INFORMATION DISCLOSURE Filing Date 03/24/2004 STATEMENT BY APPLICANT First Named Inventor G. Ramanath 2813 Group Art Unit (use as many sheets as necessary) Kielen, Erik J **Examiner Name** Sheet 5002.02-1 2 of 2 Attorney Docket Number

 	The state of the s
AQ	Reed, M.A. and Tour, J.M., "Computing with molecules," Scientific American, June 2000, pp. 86-93, Vol. 282(6).
AR	Sekiguchi, A. et al., "Microstructural and morphological changes during thermal cycling of Cu thin films," J. Japan Inst. Metals, April 2000, pp. 379-382, Vol. 64(5).
AS	ASM Handbook Vol. 5, Surface Engineering, ASM International: Materials Park, Ohio, 1994, pp. 315-318.
AT	Porterfield, Inorganic Chemistry, A Unified Approach, Addison-Wesley: Reading, Massachusetts, 1984, pp. 487-488.
AU	Moshfegh, A.Z. et al., *Bias Sputtered Ta Modified Diffusion Barrier in Cu/Ta(V <sub>b</sub> /Si(111) Multilayer Structure, Thin Solid Films, 370:10-17 (July 2000).
AV	Simon, Richard A. et al., "Synthesis and Characterization of a New Surface Derivatizing Reagent To Promot the Adhesion of Polyprrole Films to n-Type Silicon Photoanodes: N –(3-(Tarimethoxysilyl)pyrrole," J. Am. Chem. Soc., 104:2031-2034 (1982).
AW	Yin, H. et al., "Nanostructured iron-nickel thin films synthesized by electroless polyol deposition," Mater. Phys. Mech, 4:56-61 (2001).
AX	Wolf et al., "Silicon Processing for the ULSI Era," Vol. 1 – Process Technology, 2 <sup>nd</sup> Ed., Lattice Press; Sunset Beach, CA, 2000, pp. 438, 782-783.

Examiner Signature	Date Considered	
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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<sup>&</sup>lt;sup>1</sup> Applicant's unique citation designation number (optional) . <sup>2</sup> See Kinds Codes of USPTO Patent Documents at <u>www.uspto.gov</u> or MPEP 901.04. <sup>3</sup> Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup> For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup> Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. Applicant is to place a check mark here if English language Translation is attached.